

**J.C. PATENTS**

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**CERTIFICATE OF TRANSMISSION****March 11, 2003**

Atty Docket No. : MART4591  
Appl. No. : 09/759,899  
Filing Date : January, 12, 2001  
Pages : Cover + 6

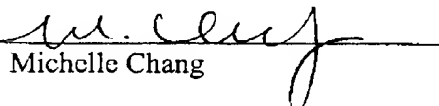
**BY FACSIMILE ONLY**

Fax No. : 703-872-9310  
Attention : Examiner AHMED, SHAMIM  
Group Unit : 1765  
From : Jiawei Huang, Reg. No. 43,330  
MESSAGE : Enclosed is an Amendment in 6 pages.

Sir:

I hereby certify that this correspondence is being facsimile transmitted to the Patent and Trademark Office on **March 11, 2003** at the above indicated fax number.

Sign by

  
Michelle Chang

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Atty Docket No.: MART4591

Serial No.: 09/759,899

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of :

Application No. : 09/759,899

Filed : January 12, 2001

For : TREATMENT ON SILICON OXYGNITRIDE

Applicant : I. T. Chen

Examiner : Ahmed, Shamim

Art Unit : 1765

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No fee is believed to be due. However, the Commissioner is authorized to charge any fees required in connection with the filing of this paper to account No. 50-0710 (Order No. MART4591).

**AMENDMENT AND RESPONSE TO OFFICE ACTION****BOX Non-Fee Amendment**

Assistant Commissioner of Patents and Trademarks  
Washington, DC 20231

Dear Sir:

The Office Action mailed on December 12, 2002 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.

**In The Title:**

Please substitute the following clean copy title for the pending title:

--METHOD TO REMOVE SILICON OXIDE MATERIAL GENERATED DURING  
REMOVAL OF PHOTORESIST--